



Heterojunction Based Hybrid Si Nanowire Solar Cell

Muhammad Y. Bashouti

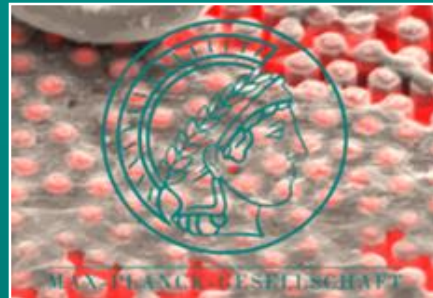
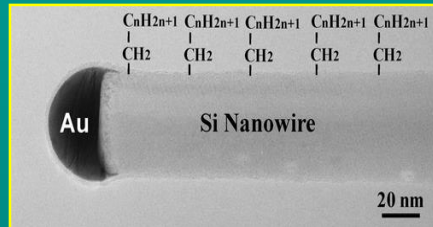
Alexandre Yersin Department of Solar Energy and Environmental Physics

Sde Boqer Campus, BGU

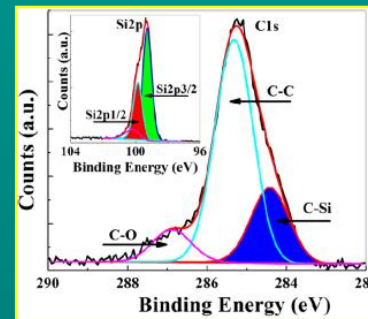
Material Growth



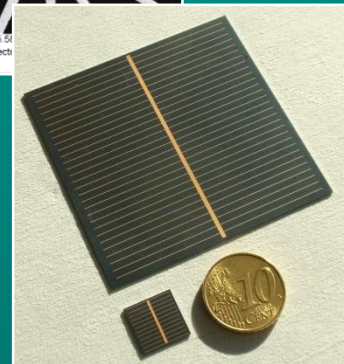
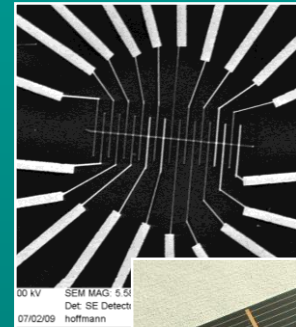
Surface Engineering



Characterization



Devices prototype





Introduction

Important Features of Nanowires
Obstacles
Molecules

First Chapter: Growth of Silicon Nanowire

Top Down

Second Chapter: Surface Treatment & Characterization

Termination with Molecules: Grignard Reaction
Surface Transfer Doping

Third Chapter: Devices

Solar Cell



Introduction

Important features of Nanowires

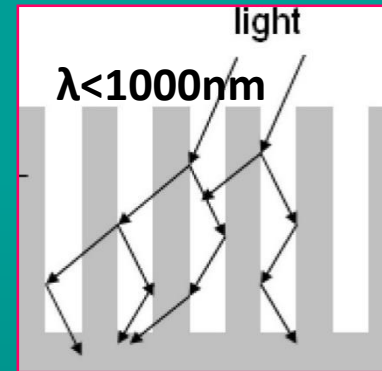
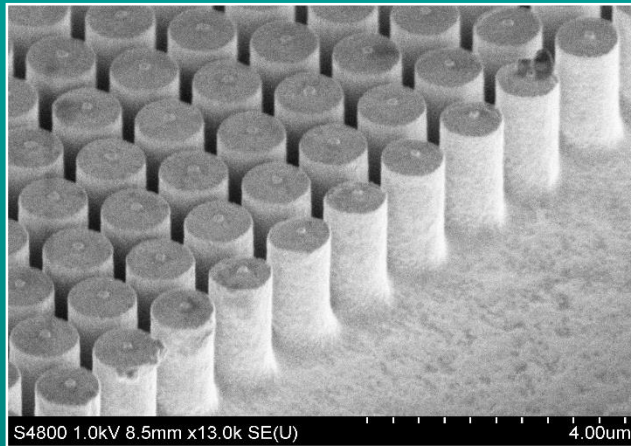
Obstacles

Molecules

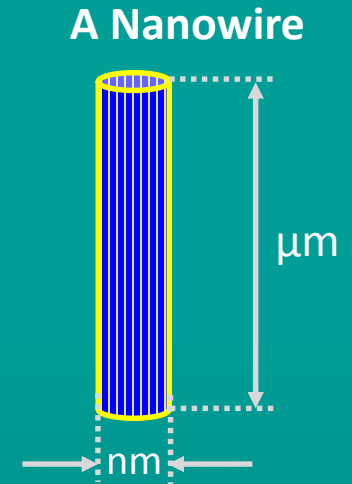


Important features of Nanowires

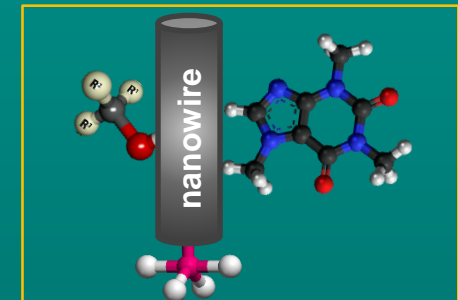
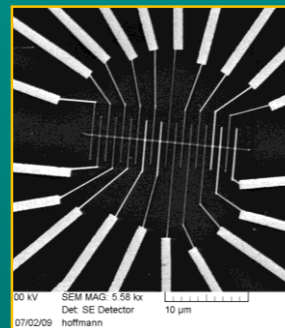
- They represent the smallest efficient transport
- Increased surface scattering
- Orthogonal Junction



Reflection $\sim < 10\%$



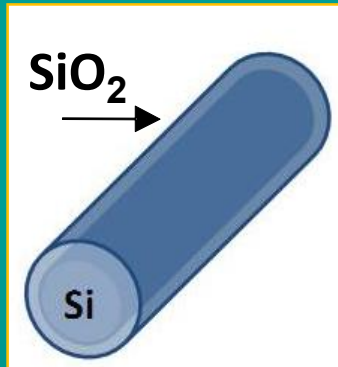
- Increased surface area
- Integration & Devices





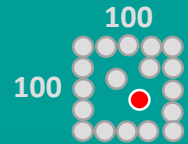
Obstacles for nanowire growth and surface modifications:

Native oxides



Lowest surface densities ever reported with thermal oxides! $\sim 10^{10}$ cm^{-2} (Si surface density $\sim 10^{14}$ cm^{-2}). However:

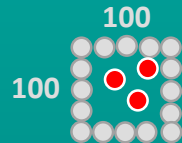
Amorphous oxides: (i) Dangling bonds



(ii) Induces trap states at the SiO_2/Si interface

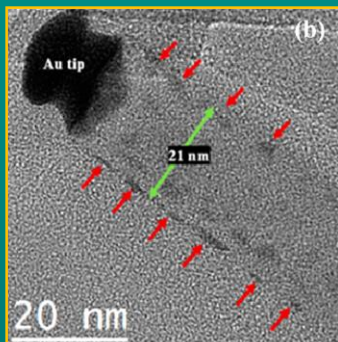
(iii) Limits the effect of gate voltage

(iv) No direct chemistry with Si



N. Lewis et al. *JACS*, (2006): 128, 8990-8991.

Gold diffusion



Gold can behave as a catalyst. However:

(i) has a high diffusion coefficient 10^{-6} cm^2sec (10^{-9} - 10^{-14}) at 1100°C

(ii) Induces deep states inside the band gap

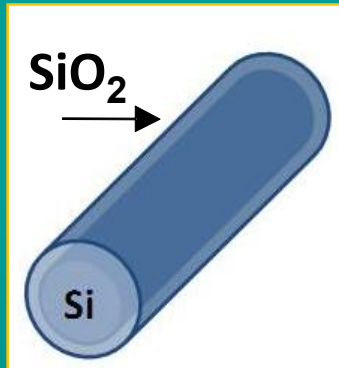
H. Haick, et al. *ACS Appl. Mater. Interf.* (2012): 4, 4251.



Obstacles on the Road

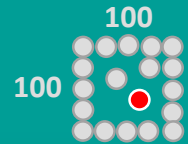
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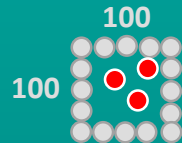
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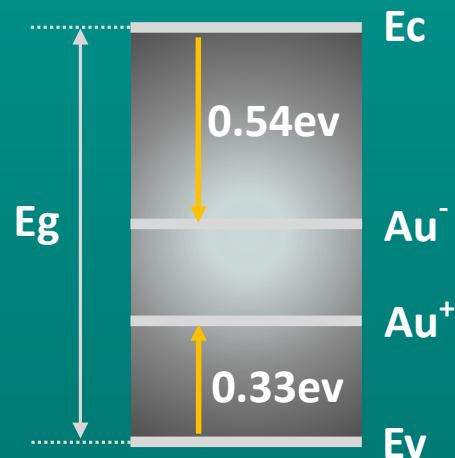
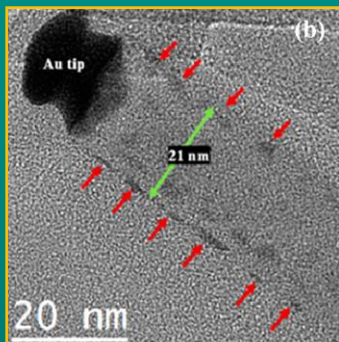
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Gold diffusion



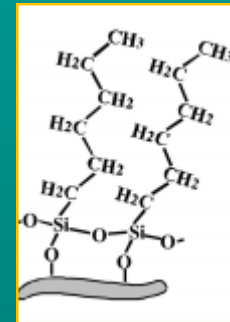
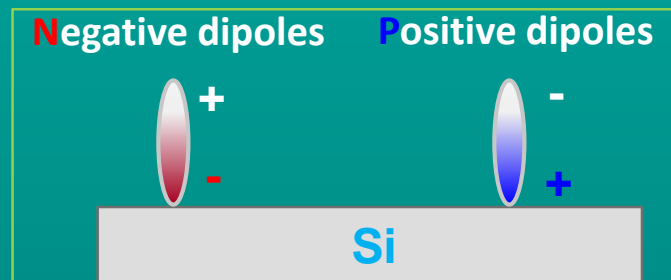


Advantages of using Molecules

A promising approach to overcome the aforementioned obstacles is to use molecules. Main advantages are as follows:



- Terminating dangling bonds \Rightarrow low surface state density
- Systematic dipoles \Rightarrow (work function design, surface dipoles)



- Controlling the molecular density
- Controlling cross-linking
- Stabilizing the surface (superior oxidation resistance)
- Molecular surface transfer doping: Controlling the doping level and type (p or n) through organic molecules.



Chapter 1

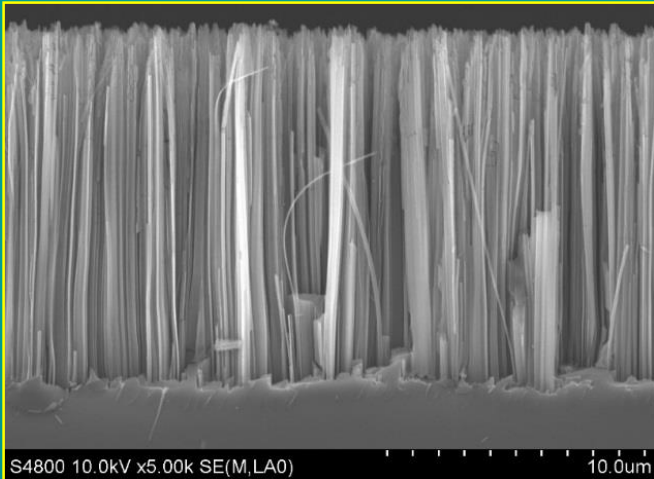
Realizing **Si Nanowires** (Si NWs)

Top Down (Wet and dry etching)

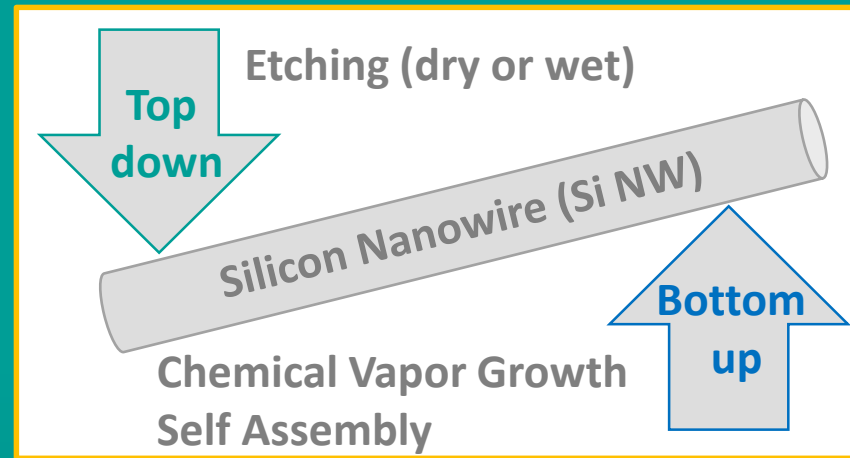
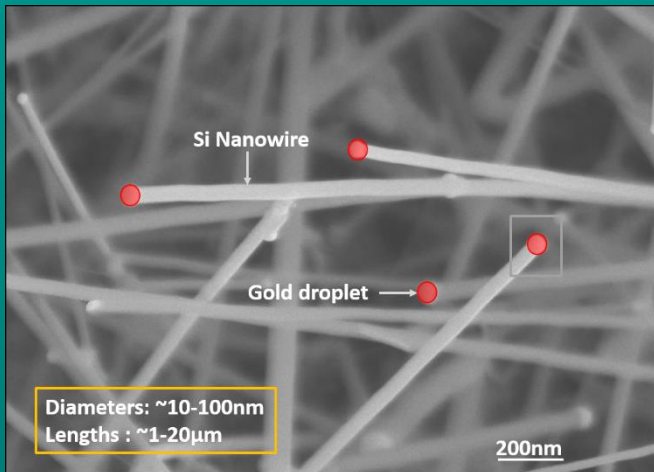


Realizing Si Nanowire: Top down

Top down approach: Wet etching



Bottom Up: CVD process



Main Advantages wet chemistry

- No need for special equipment's
- Fabricating Si NWs in a few minutes
- Large areas (4 inch)
- High aspect ratio
- Diameter of sub-micro

Bashouti, Y. M.; *at. el.* (2013): Progress in Surface Science, 88, 39-60. (Invited Review)



Realizing Si Nanowire

Top down approach: Wet etching (two step process)

Si Wafer (100)

Step 1 (5-60)s

Solution 1 (masking)
 AgNO_3/HF



Si Wafer (100)

Ag layer

Step 2 (0.5-60)min

Solution 2 (etching)
 $\text{H}_2\text{O}_2/\text{HF}$

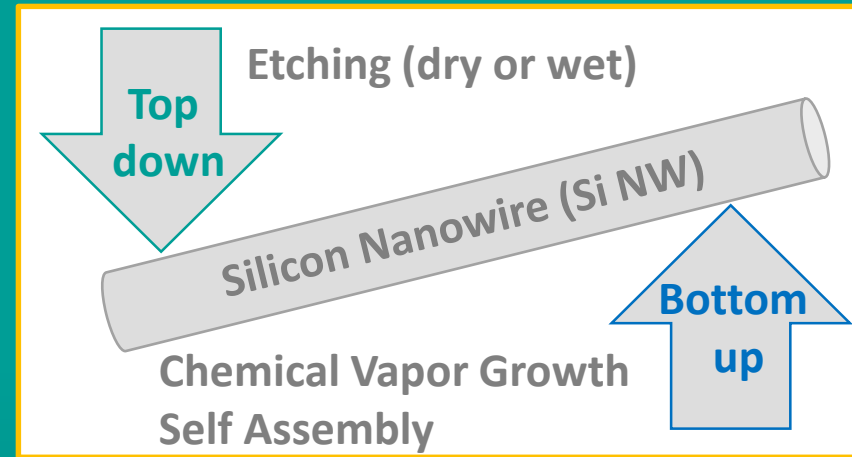


Si Wafer (100)

HNO_3

Si Wafer (100)

"Si NW"



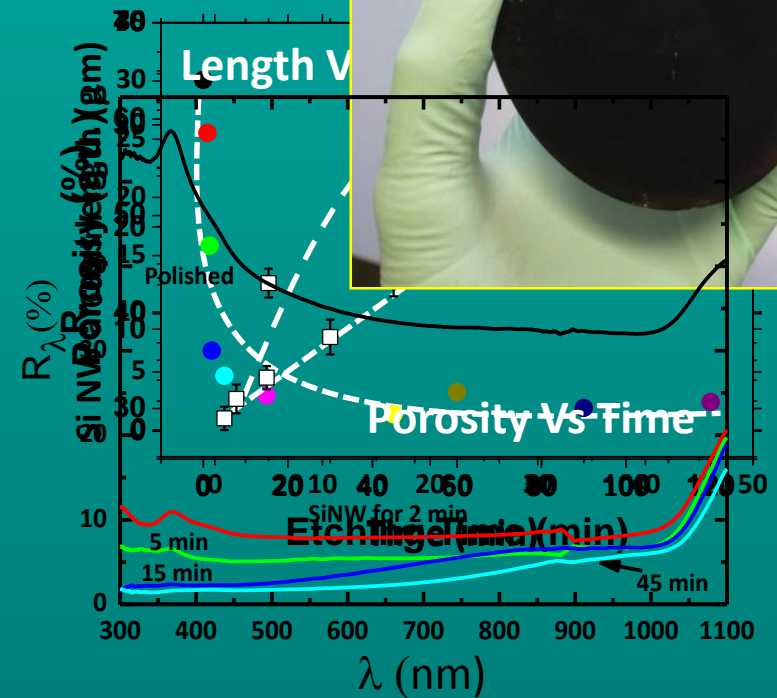
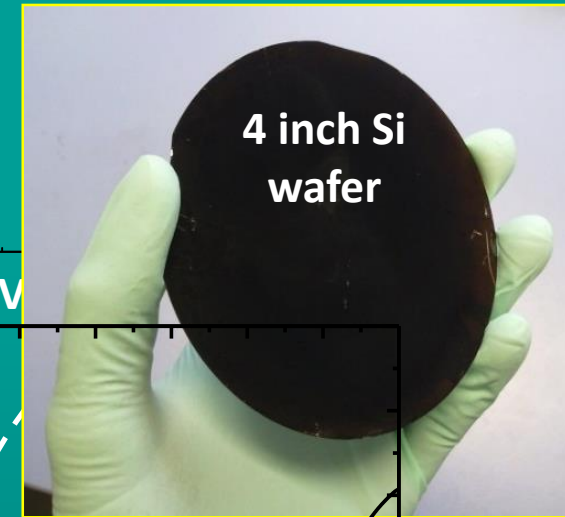
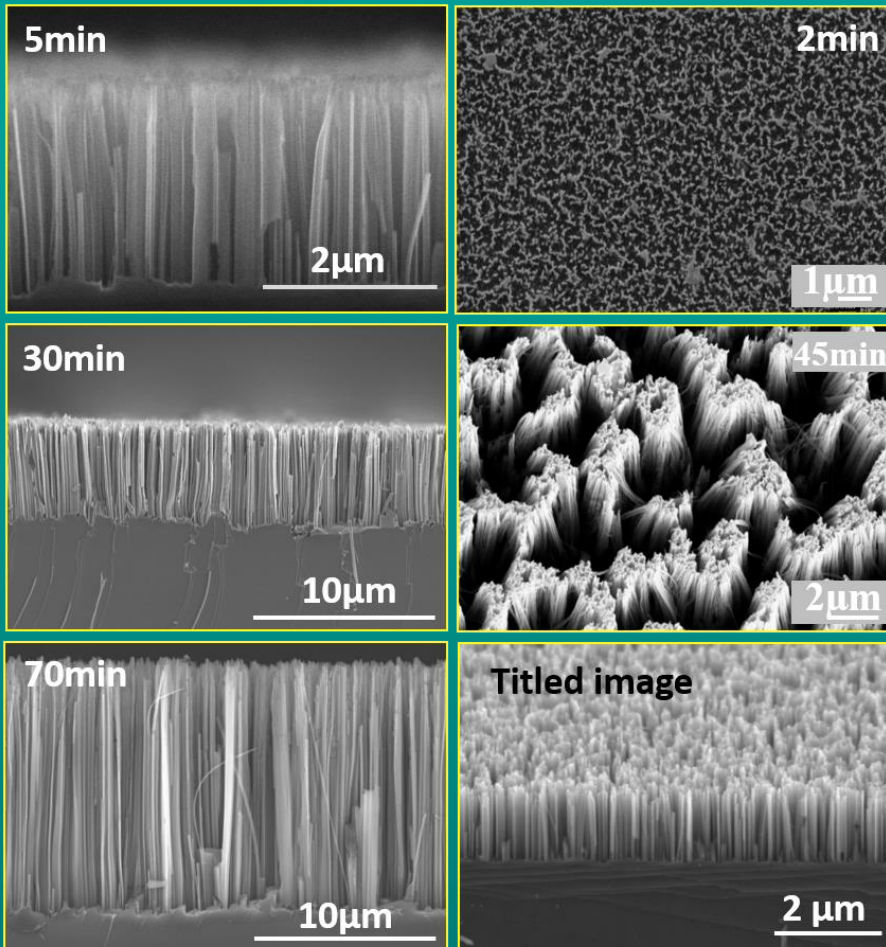
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- Fabricating Si NWs in a few minutes
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- High aspect ratio



Top down approach (wet etching) *Cont.*

Top down approach: Wet etching
(two step process: step II – Etching time)





Top down approach (wet etching) *Cont.*

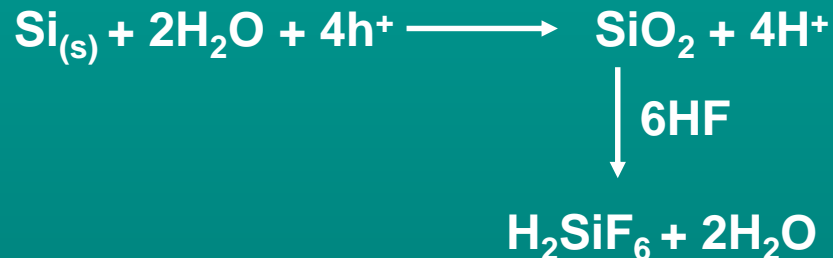
Top down approach: Wet etching (the mechanism)

Nano local electrochemical reaction

Cathode Reaction:



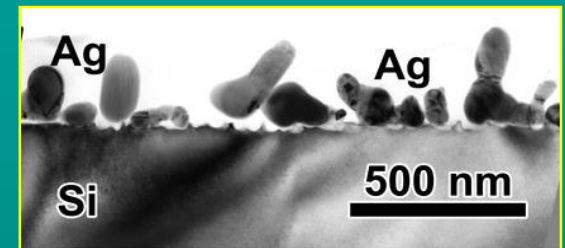
Anode Reaction:



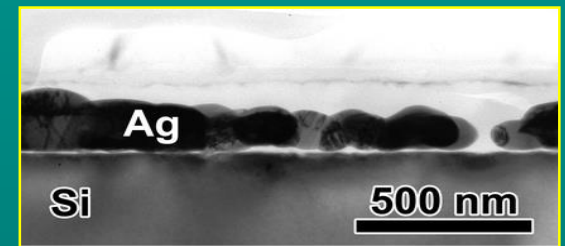
Total Reaction



(i) 15sec



(ii) 30sec





Top down approach (wet etching) *Cont.*

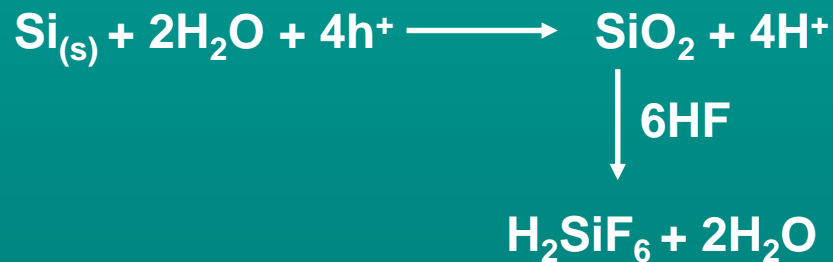
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Nano local electrochemical reaction

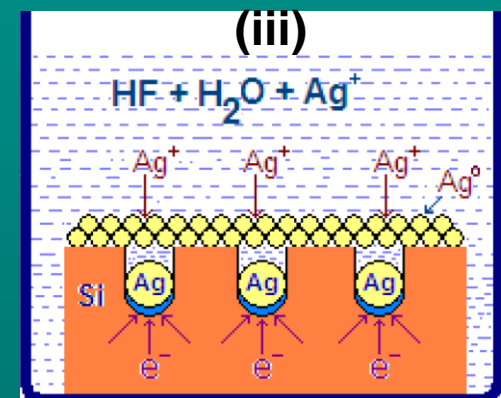
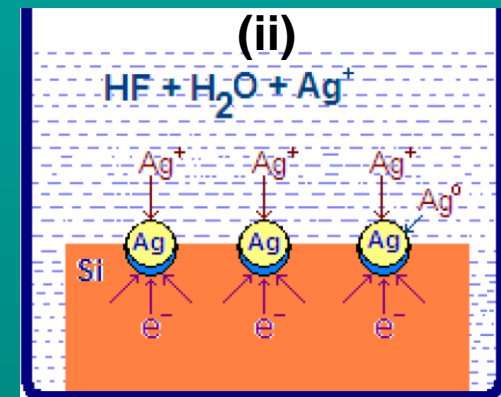
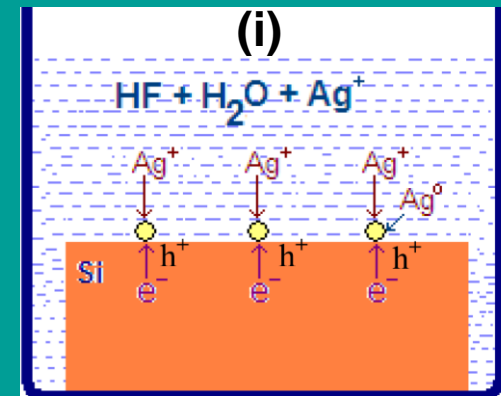
Cathode Reaction:



Anode Reaction:



Total Reaction





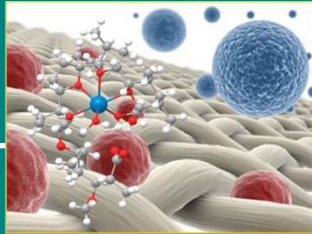
Chapter 2

Surface Treatment & Characterization



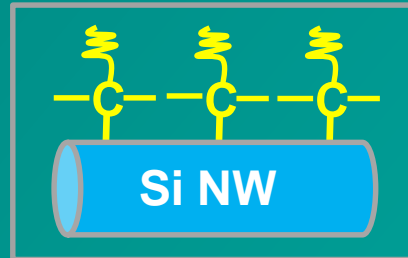
Surface Modification

Nanoparticles



Molecules

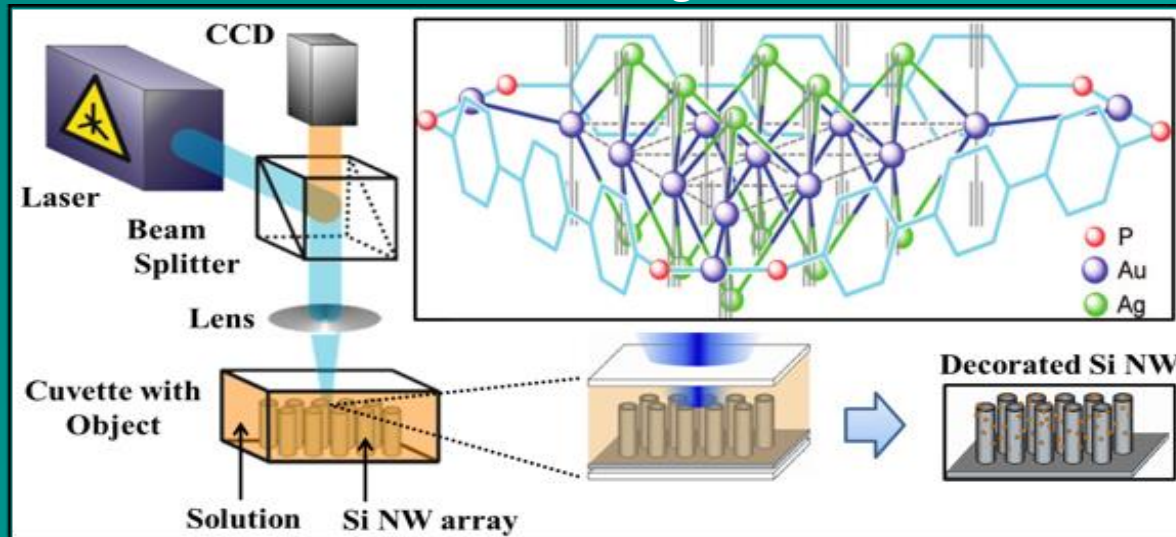
Molecules on Surfaces
(Grignard Reaction, Electrografting)



Phase Transfer
(From Cubic to Wurtzite)



Direct Laser Writing



Bashouti, Y. M. et al. (2016):
Sci. Rep. Accepted

Bashouti, Y. M. et al. (2015):
Lab-on-Chip, 15, 1742-1747.
DOI: 10.1039/c4lc01376j



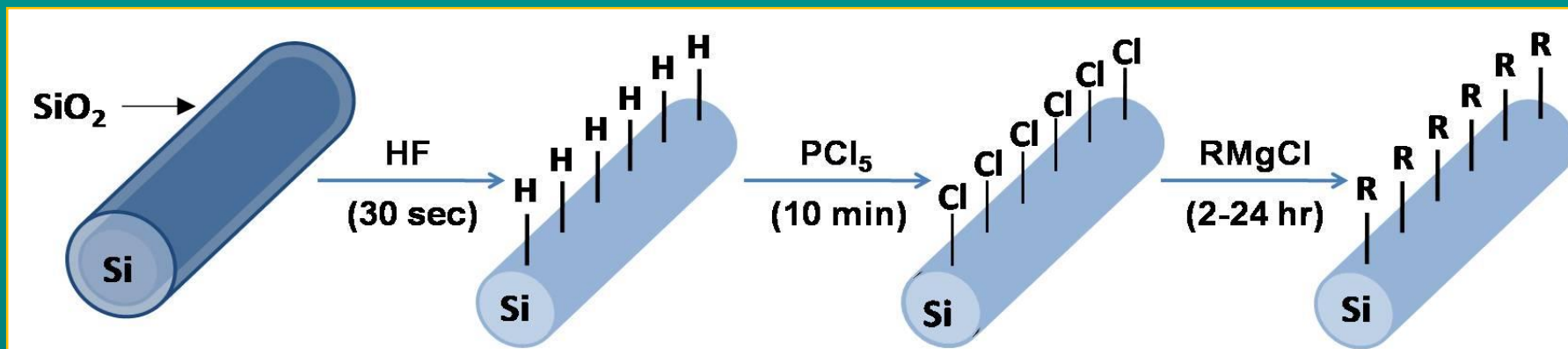
Molecules on Surfaces: Grignard Reaction

Molecules on Surfaces: Grignard Reaction

- 1) Characterization/alkylation process
 - 2) Replacing oxide shell?
 - 3) Etching: Removes the native oxide layer (makes H-Si)
 - 4) Maximum Coverage? Replaces the H by Cl
 - 5) Stability?
 - 6) Alkylation: Terminate the Si-Cl to Si-R
- Oxidation Mechanism



Two Steps Reaction

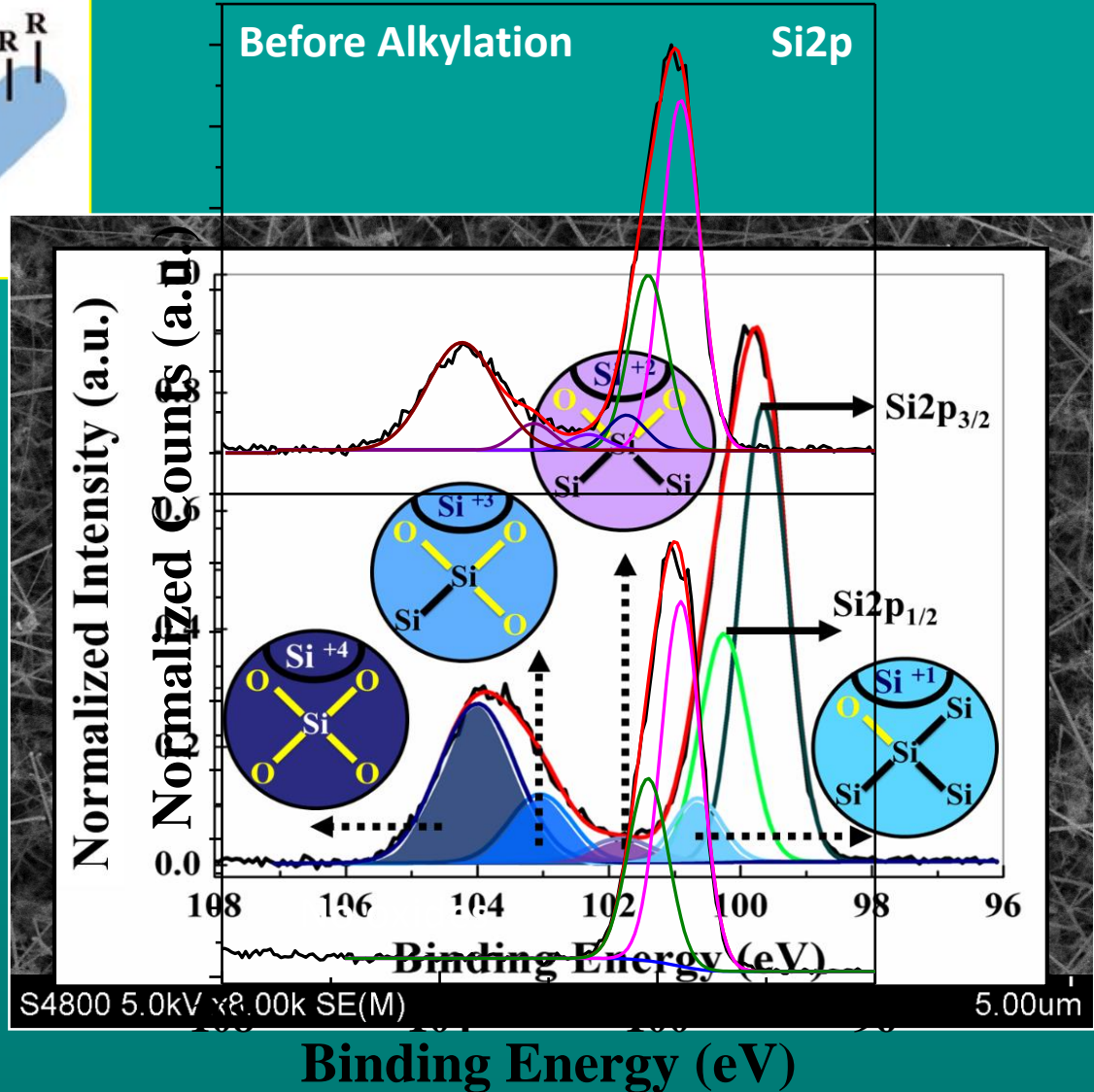


M. Y. Bashouti, *at. el.* (2008): JPCC, 112, 19168-19172.

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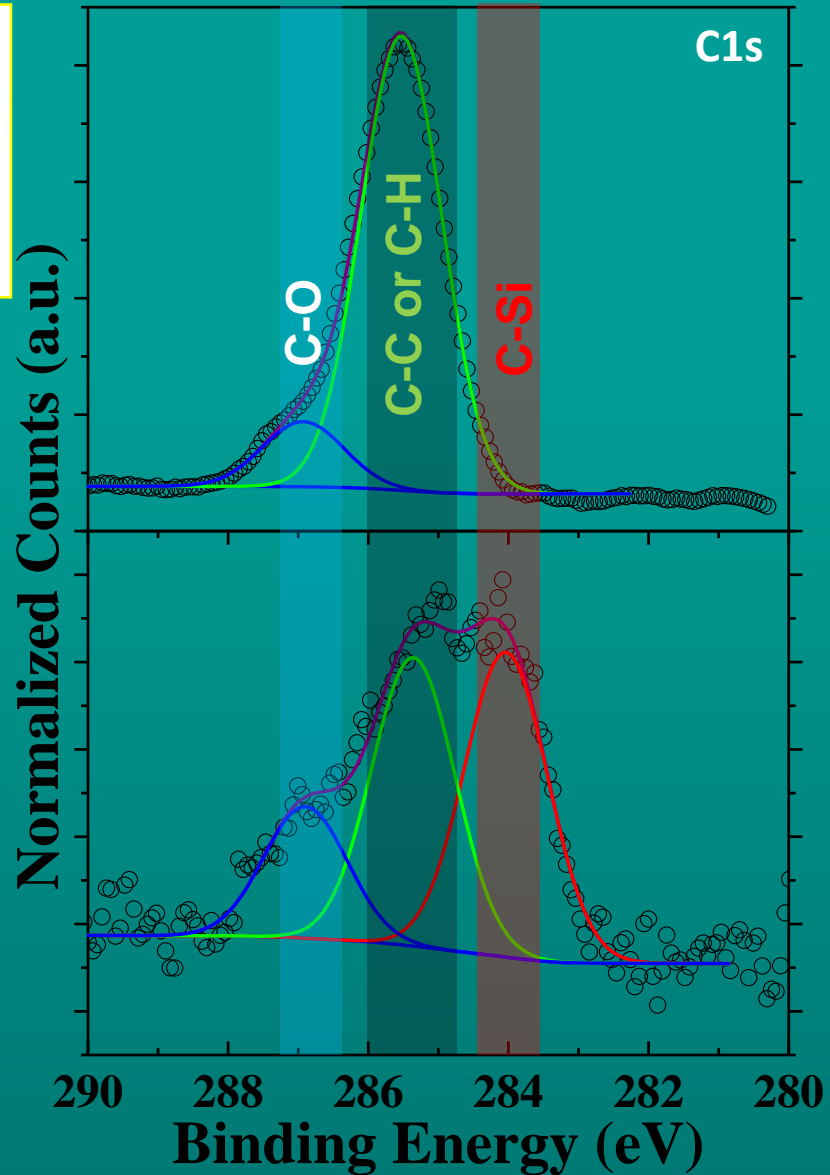
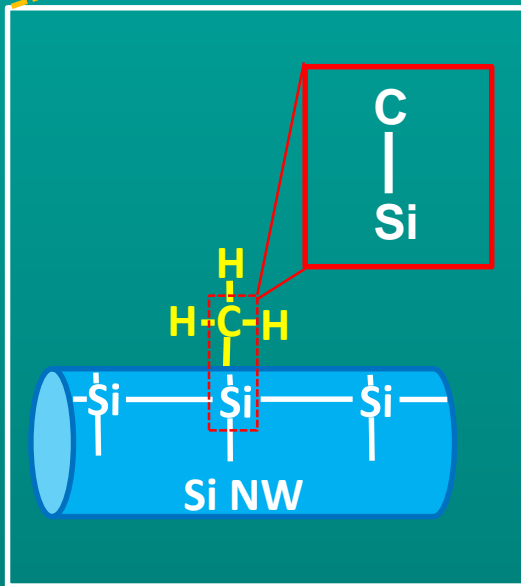
Si2p & C1s of Terminated Si NW



M. Y. Bashouti, et al. (2012): Phys. Chem. Chem. Phys., 14, 11877-11881.



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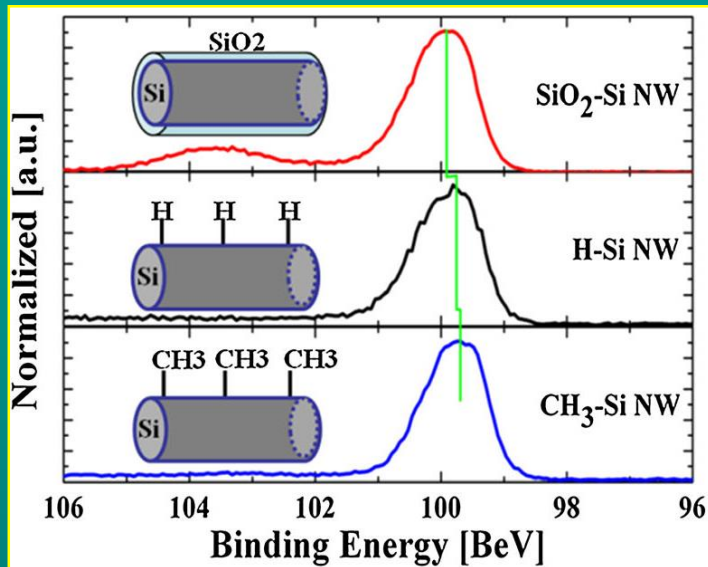
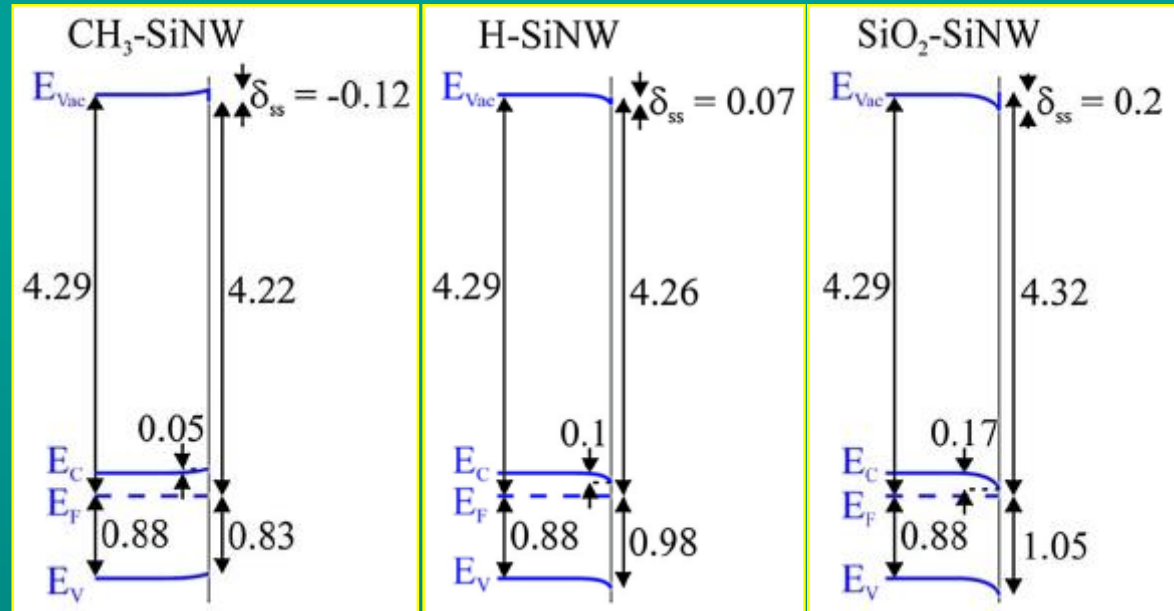


Impact on Density of State (DOS) In Suite Measurements

We followed the DOS by using the following:

1. Emission of Si2p
2. Photo-electron Yield (PYS)
3. Work-Function

Band diagram of CH₃-SiNW, H-SiNW and SiO₂-SiNW surfaces. All the numbers are in eV unit.



$$\chi_s = \Phi - E_g + (E_F - E_V)$$

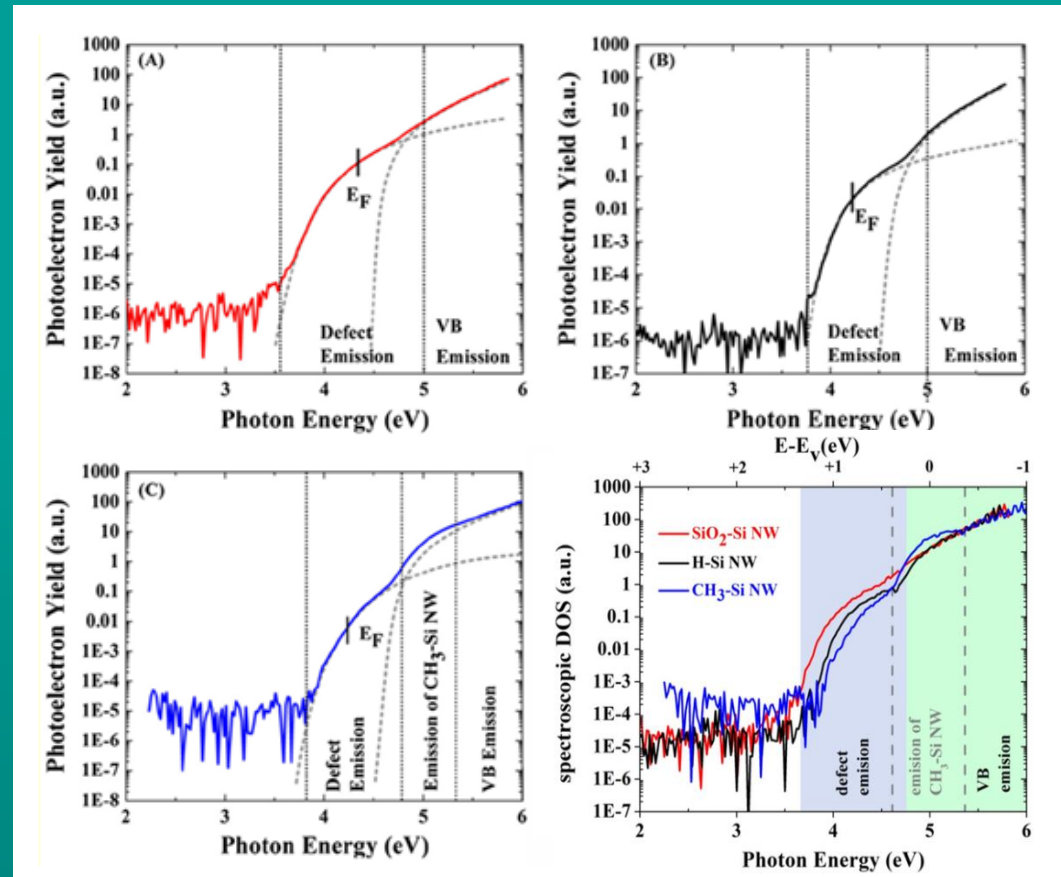
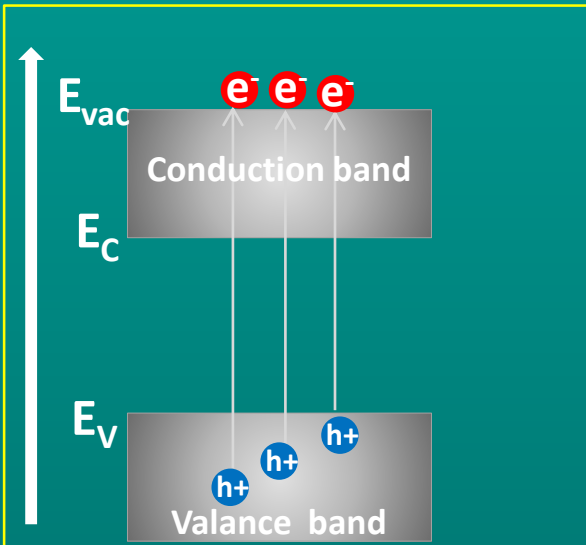
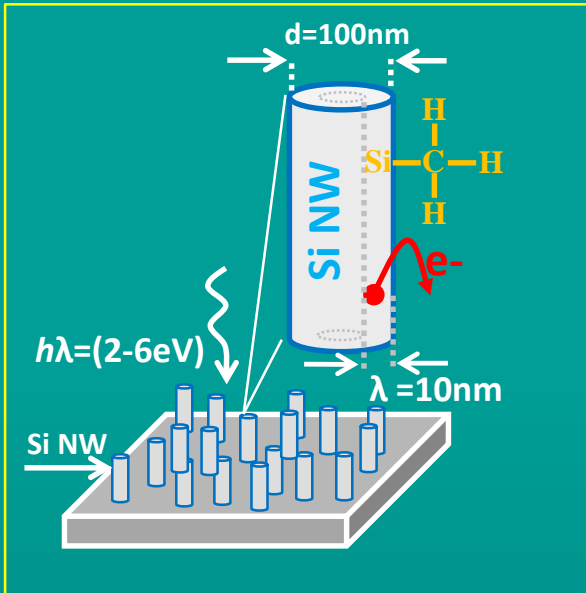
$$\delta = \chi_s - \chi_B$$

	Si2p	EF-EVBM	Φ
SiO ₂	99.77	0.83	4.32
H	99.70	0.98	4.26
CH ₃	99.55	1.05	4.22

M. Y. Bashouti *et. al.* (2014): *Prog. Photovolt: Res. Appl.* 2, 1050-1061.



Photoemission of Hybrid Si NW



$$g_{oc}(E_{VL} - \hbar\omega) \propto \frac{dY}{d(\hbar\omega)}$$

g_{oc} = occupied density of states
 E_{VL} = Vacuum Level
 $\hbar\omega$ = optical excitation



Chapter 3: **D**evices **S**olar **C**ells

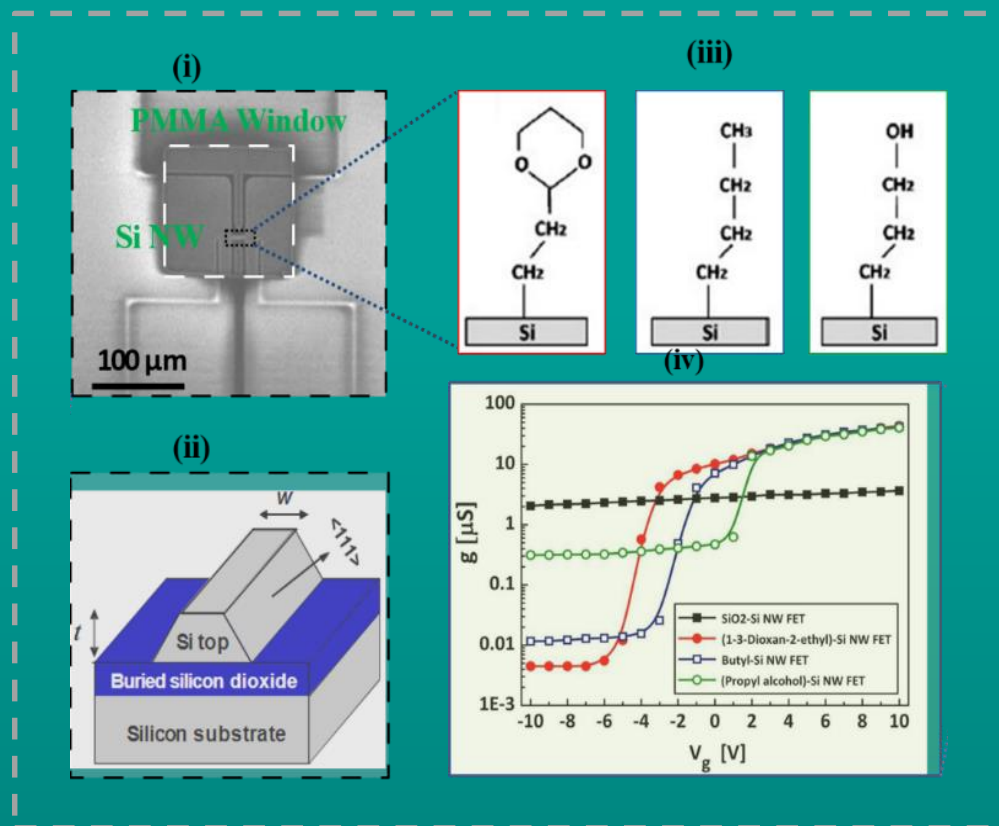


Projects: Brief Summary

Surface modifications

Devices: FETs, Solar Cells, Diodes & Transparent electrodes

devices: FET

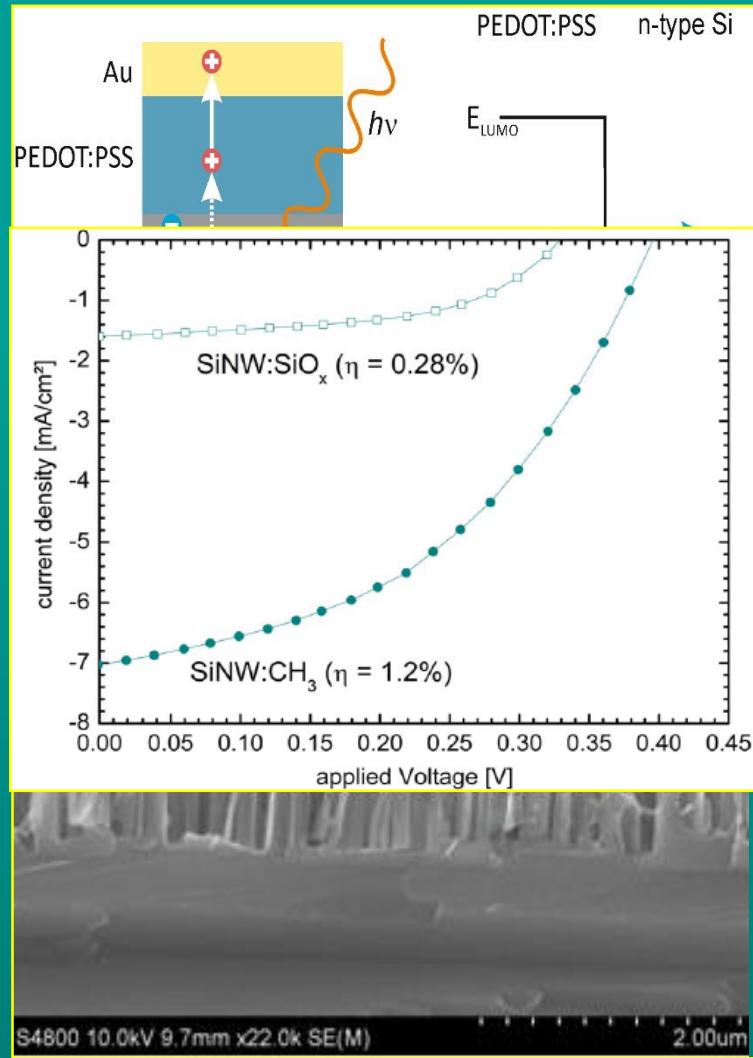


Publications:

1. M. Bashouti, et al. (2009): *Small*, 88:39-60. 5:2761-2769
2. M. Bashouti, et al. (2015): *J. Phys. Chem. Lett.*, 6:3988-3993.
3. M. Bashouti, et al. (2015): *ACS Appl. Mater. Interfaces*, 7: 21657-21661.
4. M. Bashouti, et al. (2016): *Scientific Reports*. (Accepted).
5. M. Bashouti, et al. (2016): *J. Mat. Chem.* (Under revision).



Hybrid Solar Cells: PEDOT:PSS/ Si NW

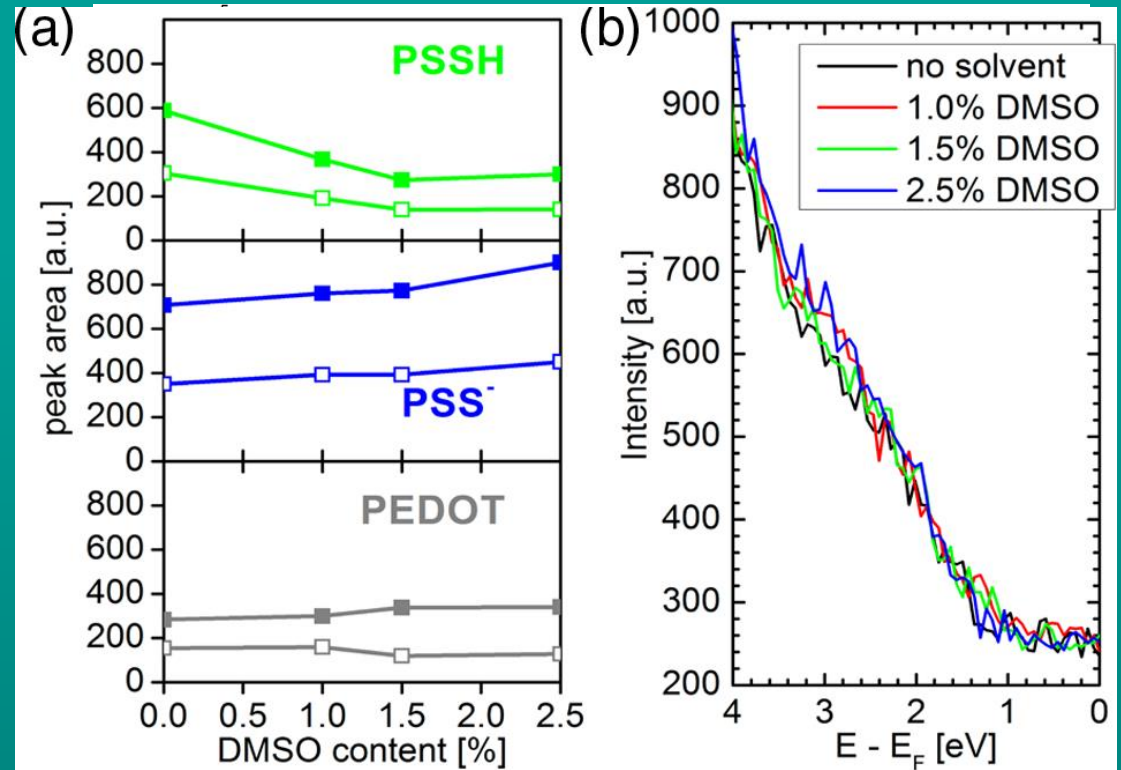


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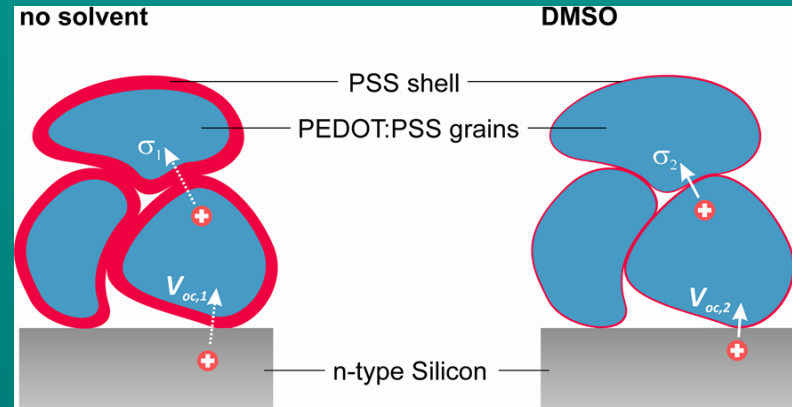
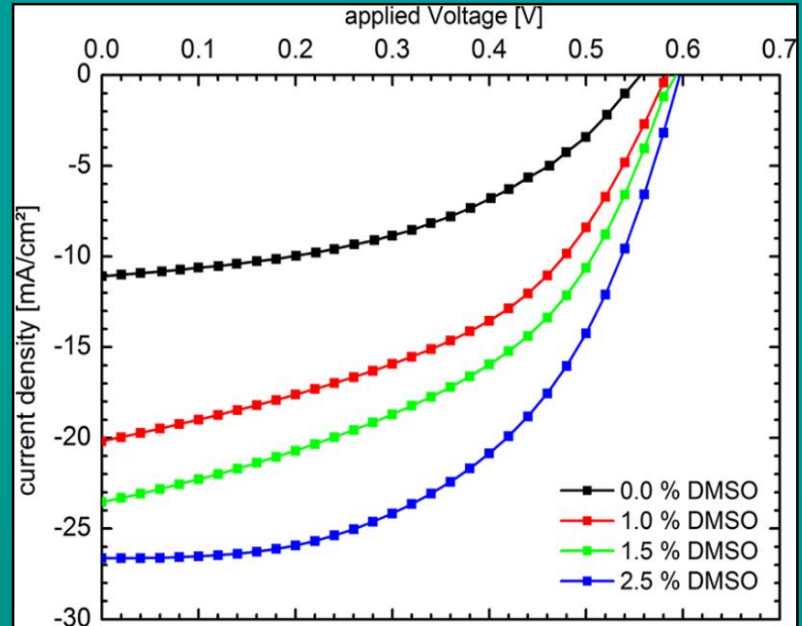


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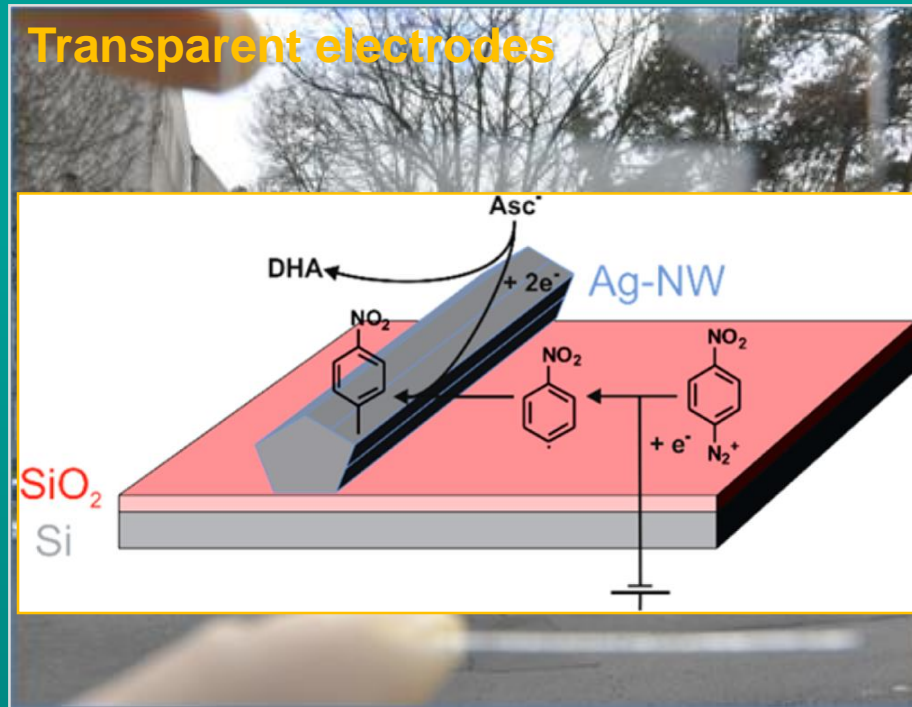
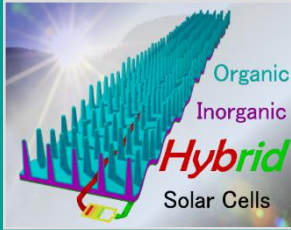


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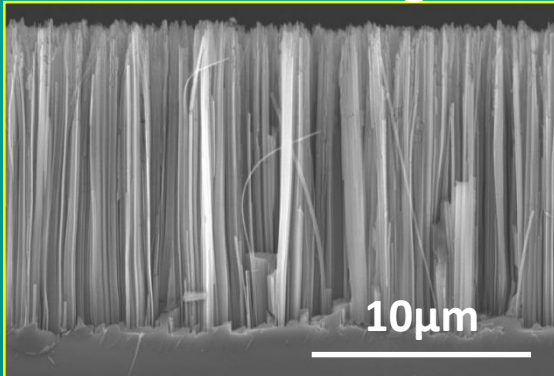


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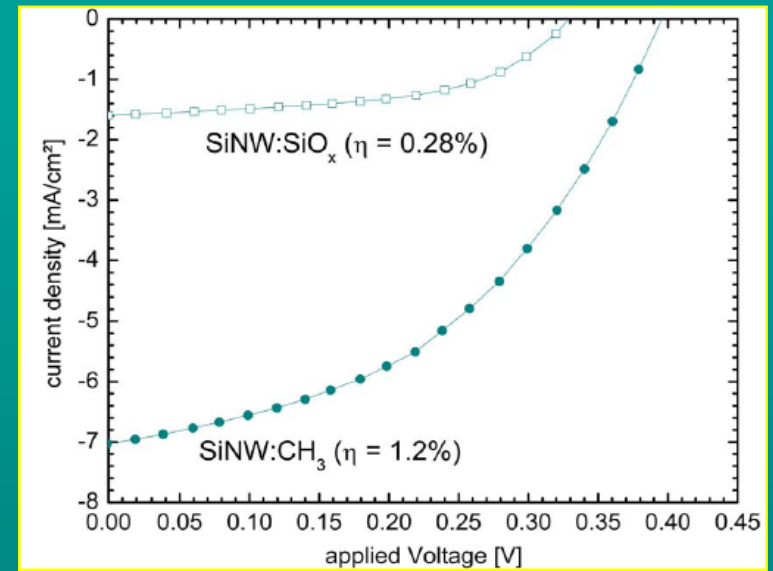
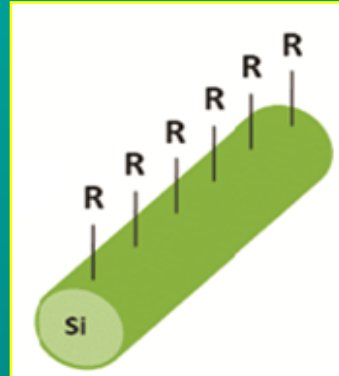
M. Bashouti, et al. (2016): *Langmuir*, (Under revision).



Wet etching



Termination





**Thank you for your
attention!**